

## Supplementary Data

### High Performance and Gate-controlled GeSe/HfS<sub>2</sub> Negative Differential Resistance Device

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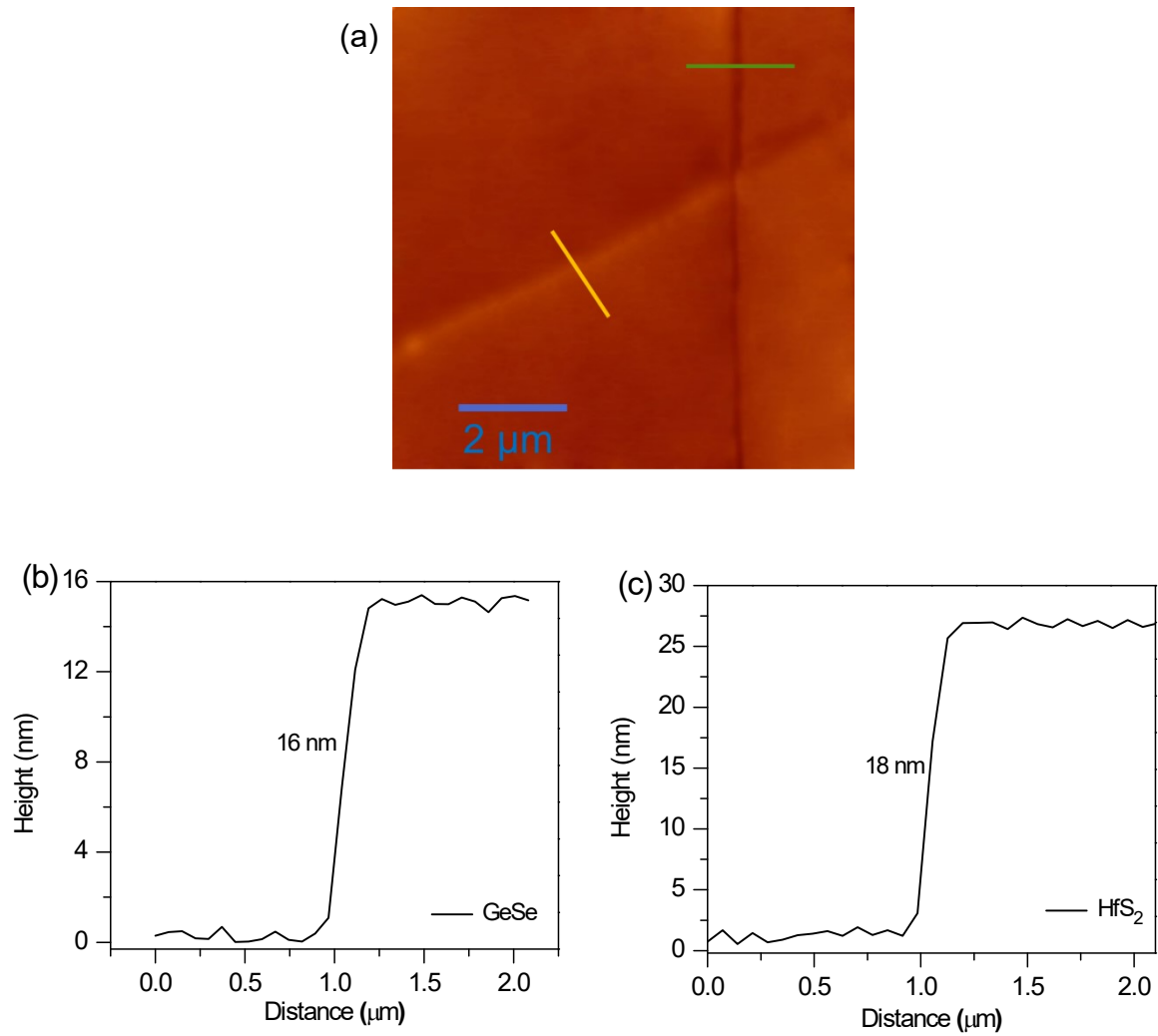
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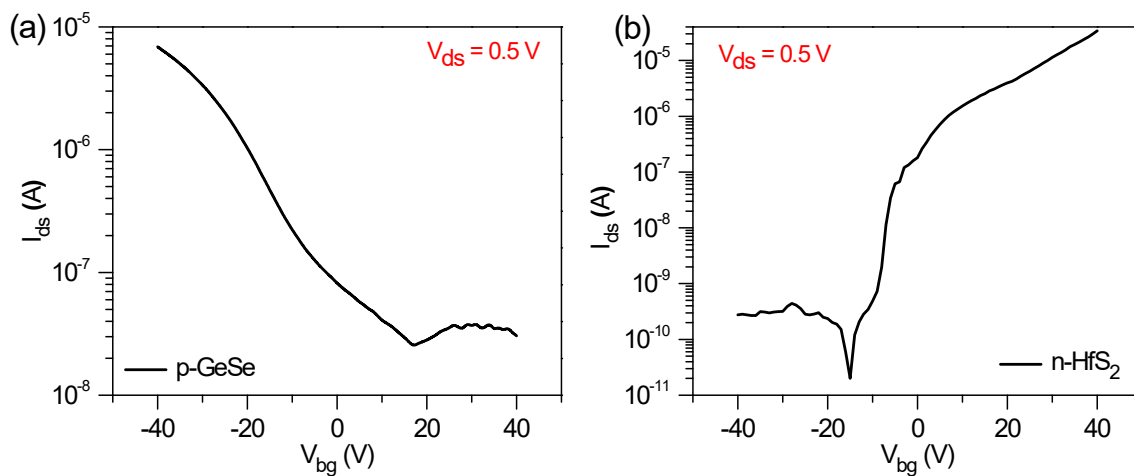
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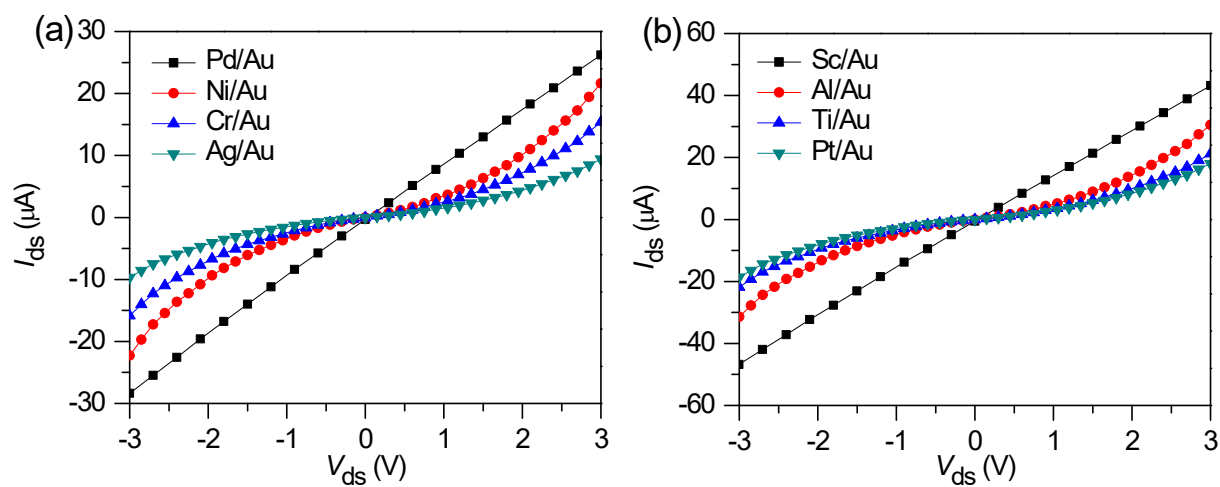
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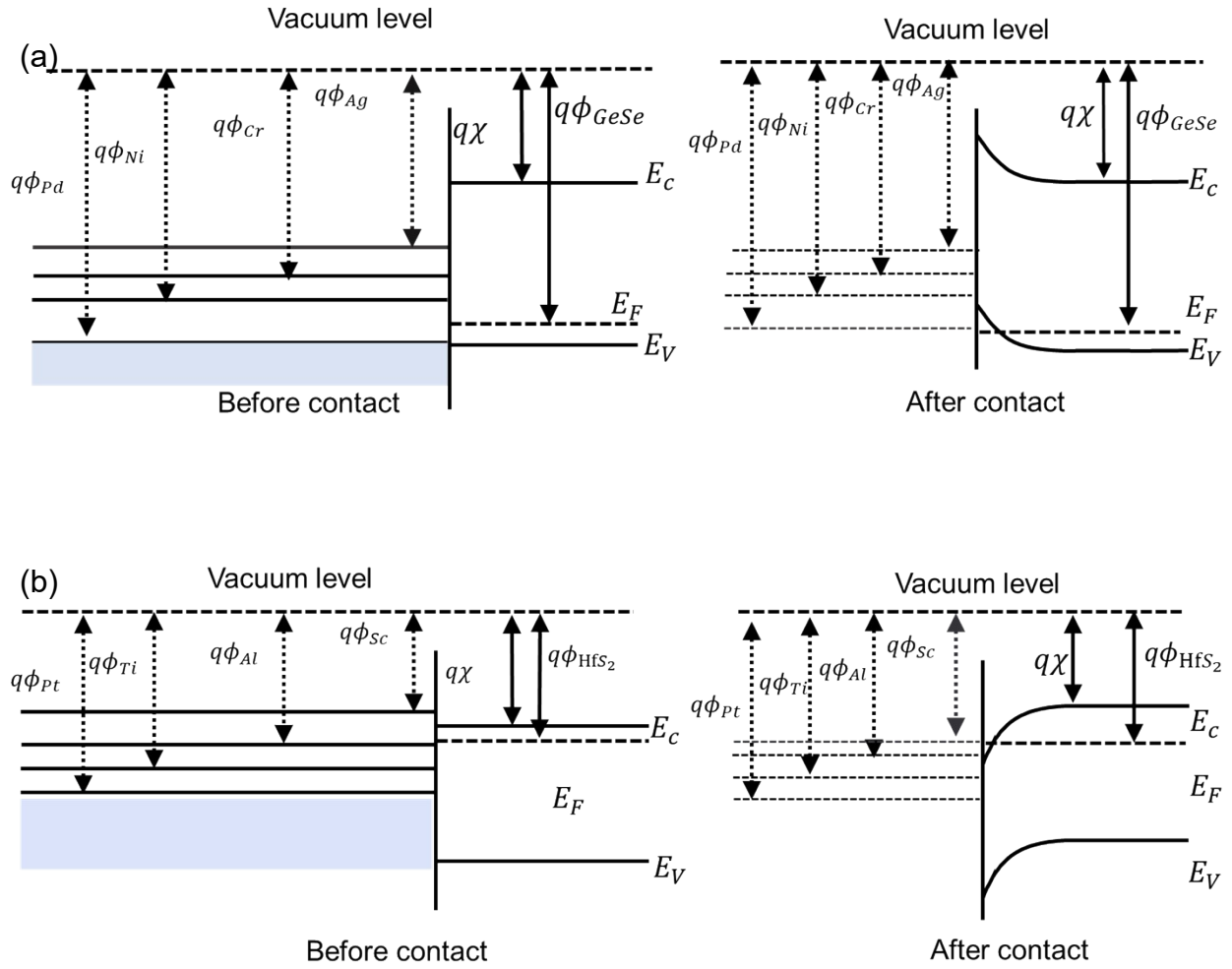
**Figure S1.** (a) Atomic force microscopy image of GeSe/HfS<sub>2</sub> heterostructure (b) Height profile of GeSe flake. The thickness of GeSe flake is 16 nm (c) Height profile of HfS<sub>2</sub> flake. The thickness of HfS<sub>2</sub> is 18 nm



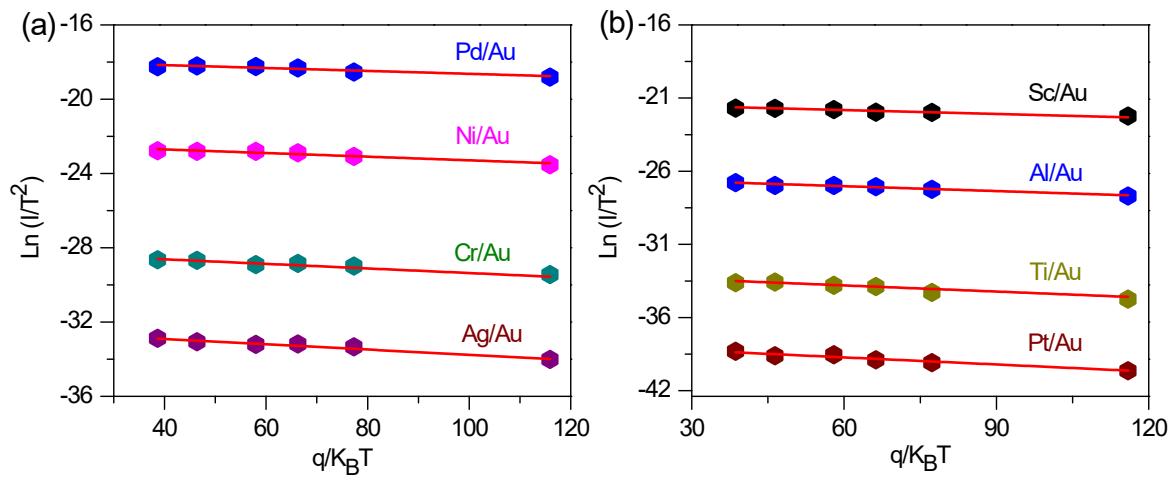
**Figure S2.** Transfer curves of (a) p-GeSe with Pd/Au (b) n- HfS<sub>2</sub> with Sc/Au



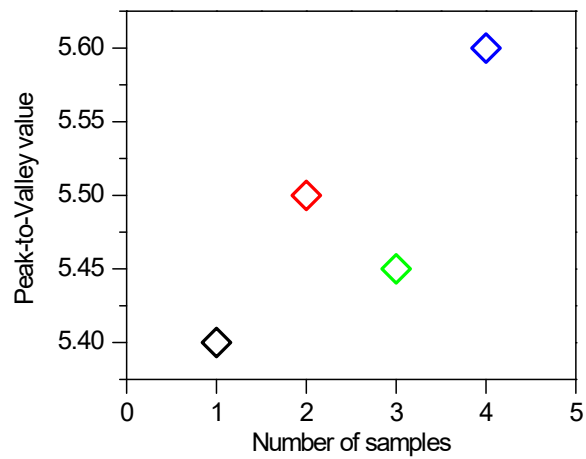
**Figure S3.** Current-voltage ( $I_{ds}$ - $V_{ds}$ ) characteristics of (a) p-GeSe with different electrodes (b) n-HfS<sub>2</sub> with different electrodes



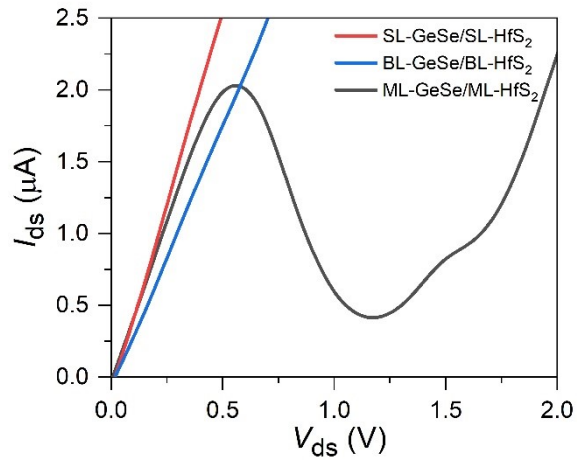
**Figure S4.** Band energy diagram of metal-TMDs (GeSe and HfS<sub>2</sub>) junction before contact and after contact (a) p-GeSe (b) n-HfS<sub>2</sub>



**Figure S5.** Richardson's plot ( $\ln(I/T^2)$  vs  $q/K_B T$ ) to calculate the barrier height for (a) GeSe (b) HfS<sub>2</sub>



**Figure S6.** Peak to valley ratio of different samples



**Figure S7.** Effect of thickness on the performance of p-GeSe/n-HfS<sub>2</sub> NDR device

Sr. No.	Heterostructure	Peak-to-valley current ratio	Ref.
1	BP/SnSe <sub>2</sub>	2.8	1
2	MoS <sub>2</sub> /WSe <sub>2</sub>	0.6	2
3	MoS <sub>2</sub> /WSe <sub>2</sub>	1.6	3
4	WSe <sub>2</sub> /SnSe <sub>2</sub>	4	4
5	BP/ReSe <sub>2</sub>	3.3	5
6	WSe <sub>2</sub>	1.5	6
7	BP/ReS <sub>2</sub>	6.9	7
8	GeSe/HfS <sub>2</sub>	9.8	This work

Table 1. Comparison of p-GeSe/n-HfS<sub>2</sub> NDR devices with previously reported value.

## References

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